

Title (en)

MICROMECHANICAL ROTATIONAL SPEED SENSOR

Title (de)

MIKROMECHANISCHER DREHRATENSOR

Title (fr)

CAPTEUR DE VITESSE DE ROTATION MICROMÉCANIQUE

Publication

EP 1994363 A1 20081126 (DE)

Application

EP 07722020 A 20070312

Priority

- DE 2007000445 W 20070312
- DE 102006012610 A 20060310

Abstract (en)

[origin: WO2007104289A1] The invention relates to a micromechanical rotational speed sensor comprising a substrate (9) and at least one base element (1) which is suspended on the substrate by means of at least one spring element (11, 11') and comprises at least one seismic mass (3), an excitation means (8) and a reading device (15). According to the invention, the spring element (11, 11') can be displaced perpendicularly to the direction of displacement (x, y) of the base element (1).

IPC 8 full level

G01C 19/56 (2006.01); **G01P 9/04** (2006.01)

CPC (source: EP KR US)

G01C 19/56 (2013.01 - KR); **G01C 19/5747** (2013.01 - EP US); **G01C 19/5762** (2013.01 - EP US)

Citation (search report)

See references of WO 2007104289A1

Citation (examination)

- DE 19641284 C1 19980520 - INST MIKRO UND INFORMATIONSTEC [DE]
- US 2005024527 A1 20050203 - CHIOU JEN-HUANG ALBERT [US]

Designated contracting state (EPC)

AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HU IE IS IT LI LT LU LV MC MT NL PL PT RO SE SI SK TR

DOCDB simple family (publication)

WO 2007104289 A1 20070920; CN 101400969 A 20090401; DE 112007000303 A5 20081030; EP 1994363 A1 20081126; JP 2009529697 A 20090820; KR 20080113048 A 20081226; US 2009031806 A1 20090205; US 8342022 B2 20130101

DOCDB simple family (application)

DE 2007000445 W 20070312; CN 200780008668 A 20070312; DE 112007000303 T 20070312; EP 07722020 A 20070312; JP 2009503398 A 20070312; KR 20087024599 A 20081008; US 22500907 A 20070312